



Attorney's Docket No.: 09712-332001 / Z-433

LFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Peter J. de Groot Art Unit : 2877
Serial No. : 10/659,060 Examiner : Marissa Detschel
Filed : September 9, 2003
Title : INTERFEROMETRY METHOD FOR ELLIPSOMETRY, REFLECTOMETRY,
 AND SCATTEROMETRY MEASUREMENTS, INCLUDING
 CHARACTERIZATION OF THIN FILM STRUCTURES

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT IN REPLY TO ACTION OF MARCH 14, 2006

Please amend the above-identified application as follows:

CERTIFICATE OF MAILING BY FIRST CLASS MAIL

I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

6-6-06

Date of Deposit

Signature

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